

Morphology-Controlled Two-Dimensional Elliptical Hemisphere Arrays Fabricated by Colloidal Crystal Based Micromolding Method

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Electronic Supporting information

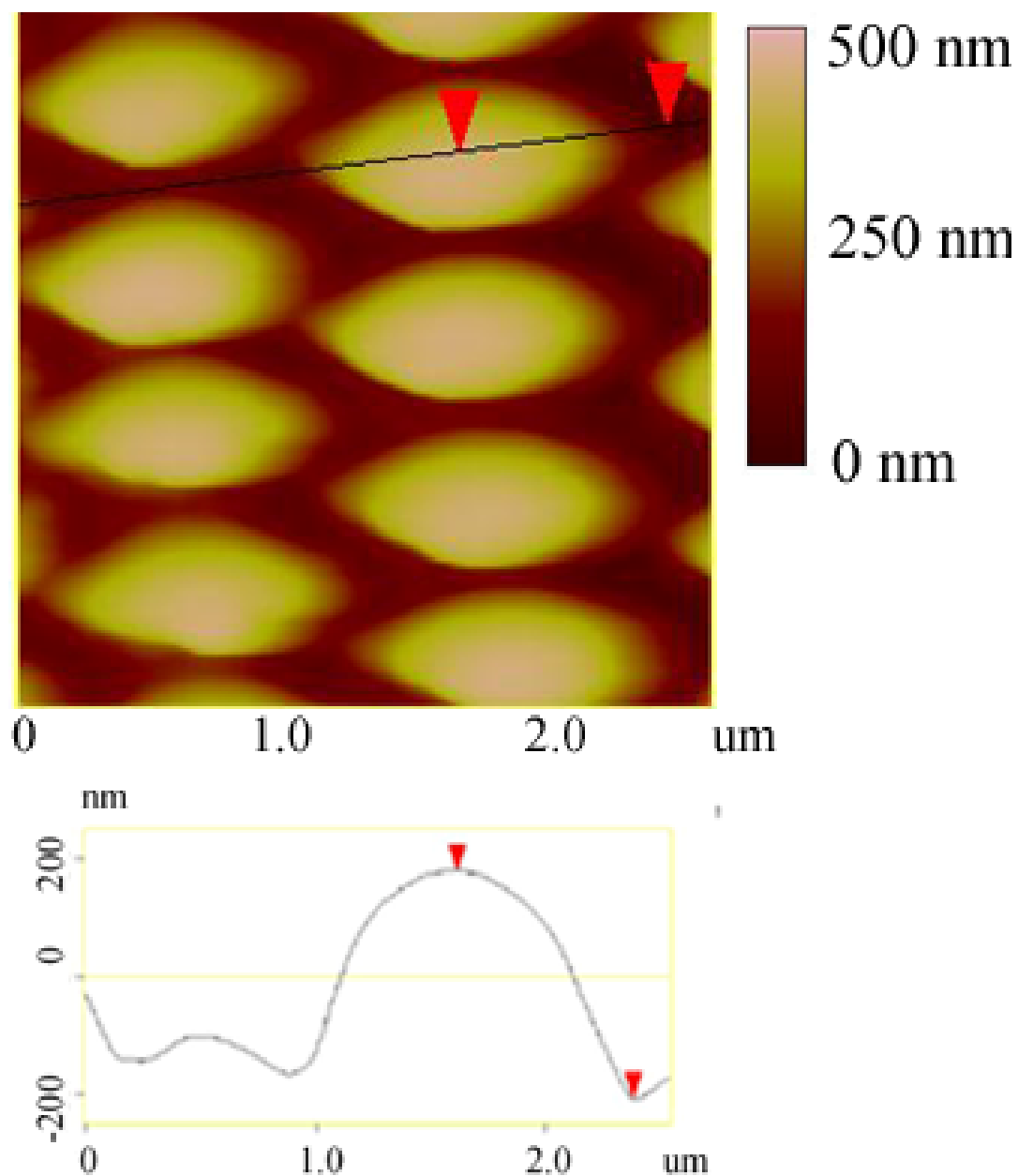


Figure S1. AFM images (left) and line profile (right) of the obtained 2D EHA of PS fabricated using the PDMS mold peeled off from the silica spheres template with diameters of 576 nm.

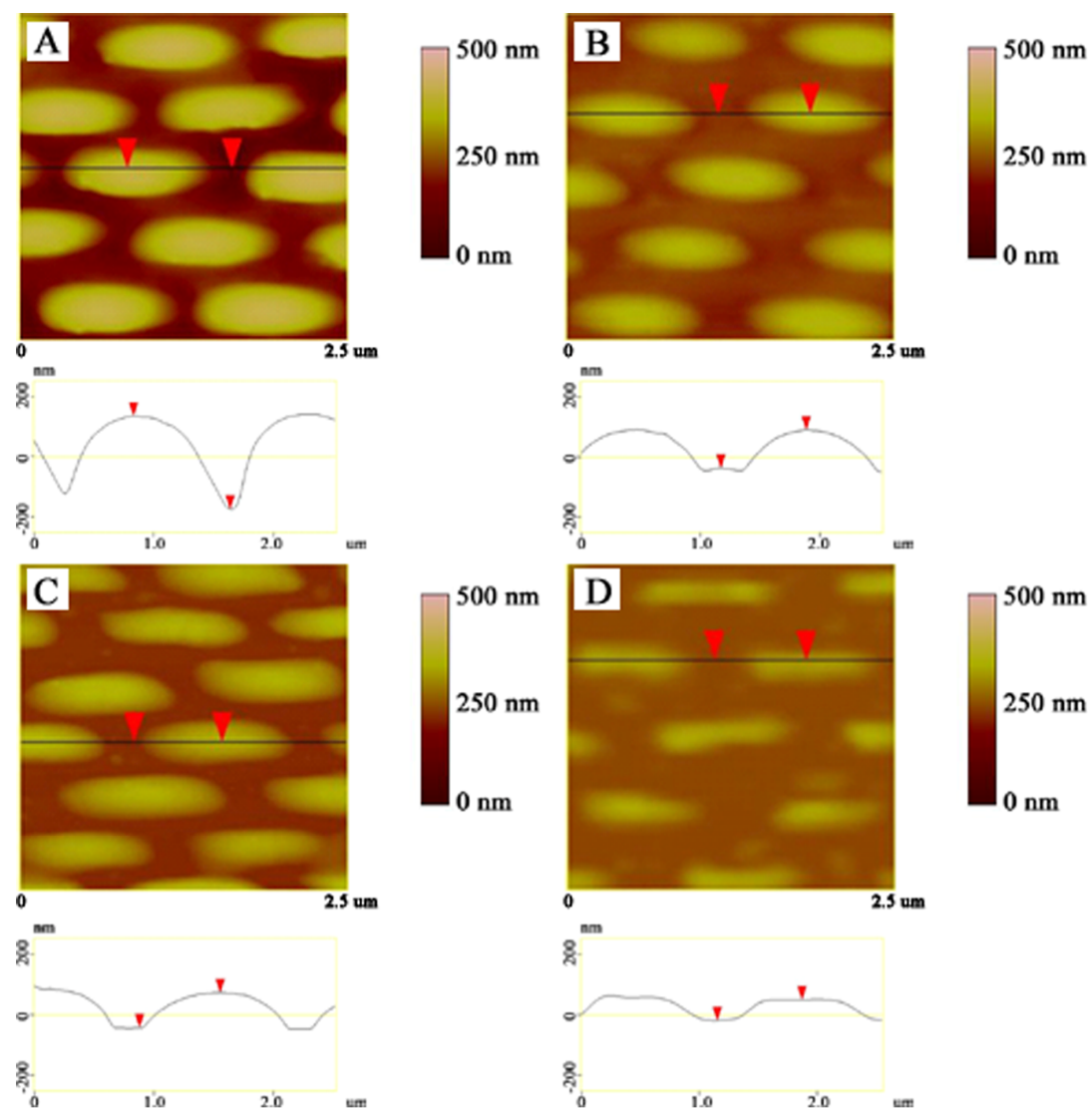


Figure S2. AFM images (top) and line profile (down) of the resulted microstructures, the thickness of the PS films is (A) 140 nm, (B) 89 nm, (C) 35 nm and (D) 11 nm, respectively.

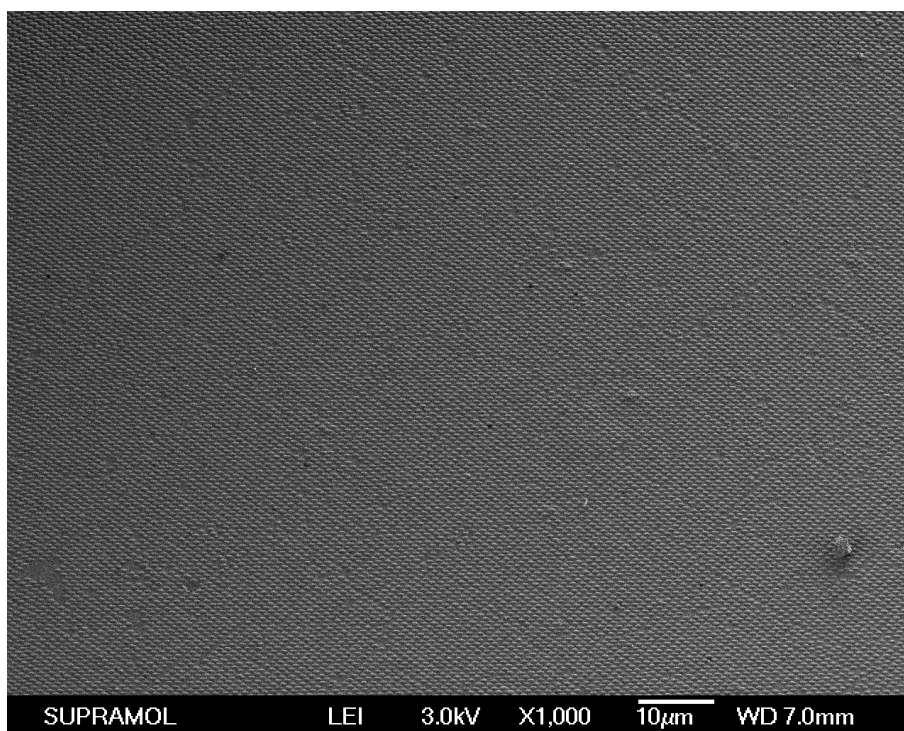


Figure S3. SEM images of EHA fabricated stretching along direction I with low magnification.

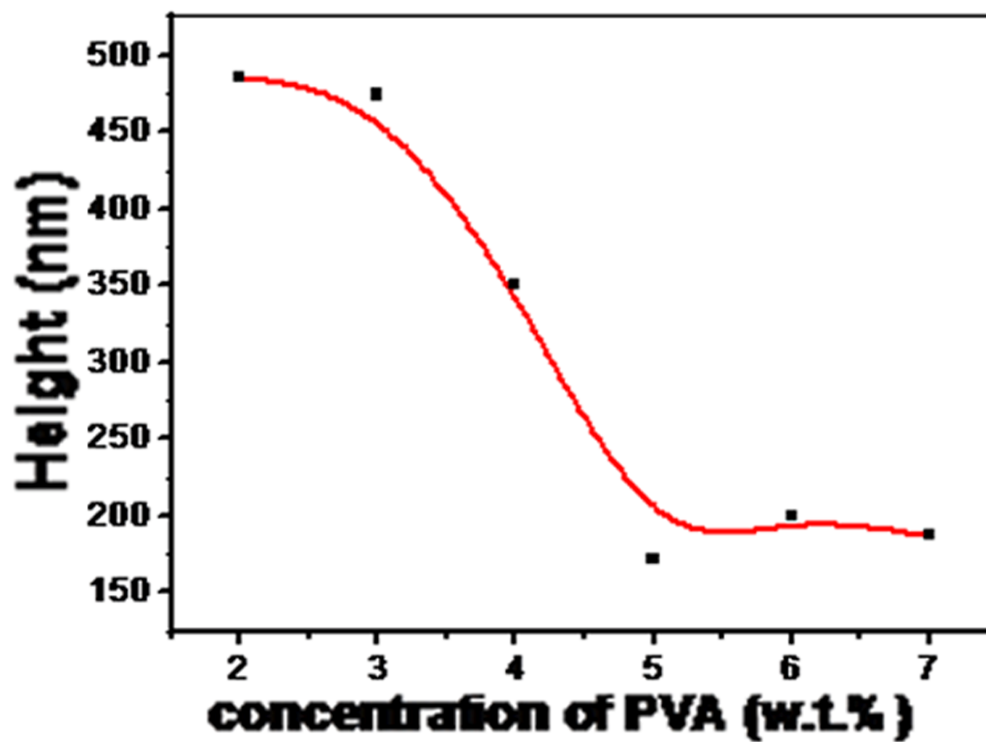


Figure S4. Height of the exposed silica spheres plotted with respect to the concentration of the PVA aqueous solution.

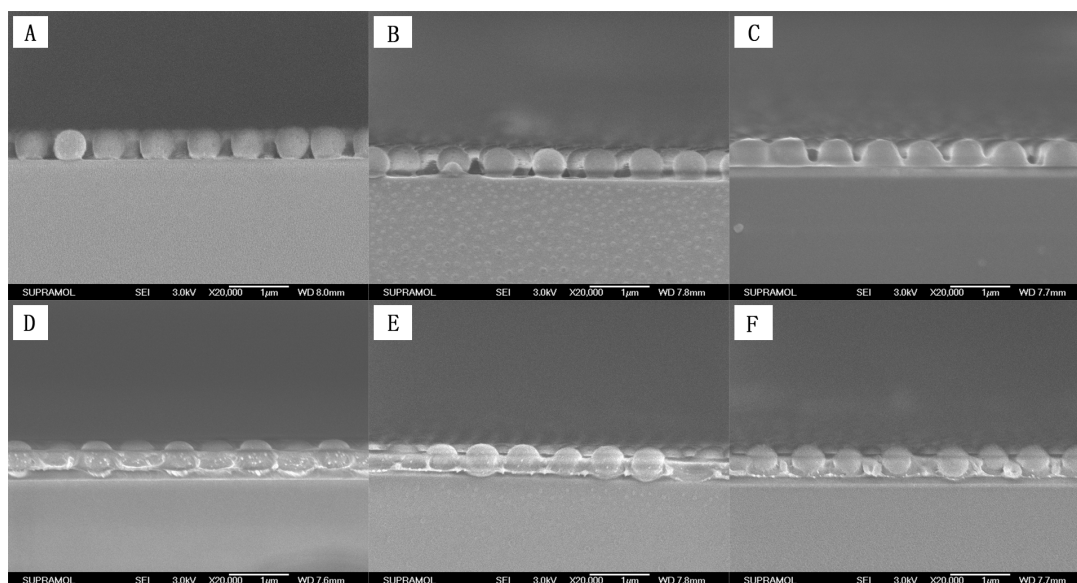


Figure S5. Cross section SEM images of the ncp silica arrays sunk into PVA film when using the PVA aqueous solution with the concentration of (A)2 wt. %, (B)3 wt. %, (C)4 wt. %, (D)5 wt. %, (E)6 wt. % and (F)7 wt. %, respectively.